## SI3401 Gas Concentration Analyzer for $NH_3$ , HF, and HCI

## ΡΙΟΔ R R Ο

AMC Monitoring for Inorganic Gases



Analytical data that improves yield with early warning of contamination events!

- Parts-per-trillion (ppt) sensitivity
- Fast, continuous measurements in seconds
- Minimum maintenance with no consumables
- No field calibration, verify with proxy gas mix of CH<sub>4</sub>, CO<sub>2</sub> and O<sub>2</sub>

## NH<sub>3</sub>, HF, and HCl 3-species AMC analyzer

Yield declines due to airborne molecular contamination (AMC) have been well documented (Ref: IRDS 2018). The **SI3401 multi-species AMC analyzer** utilizes Picarro's highly selective, sensitive, and accurate cavity ring-down spectroscopy (CRDS) for real-time measurement of three gases in one convenient chassis.

Designed to operate in both cleanrooms and plenums, this laser-based analyzer can operate for many months without user interaction. The analyzer can be commissioned and operating within minutes, with zero sample preparation. The gas concentration is displayed in real-time with no post-processing requirements. The analyzer can be configured to automatically export its measurement data at regular intervals, via an Ethernet or RS-232 interface.

 $NH_3$ , HF, and HCl are critical process chemicals that are routinely monitored in a semiconductor manufacturing

fab. Furthermore, the analyzer measures  $H_2O$ , eliminating the need for a dedicated humidity sensor.

The SI3401 analyzer provides parts-per-trillion level detection of the gases within seconds. It also provides the best cost of ownership via a small footprint (one analyzer to cover all three gases), lower service costs, and lower electricity consumption.

Picarro's SI3401 analyzer offers the simplicity and reliability of CRDS technology for AMC monitoring in a robust, compact, and fixed or transportable package.

Designed for long-term stability and low maintenance, this analyzer is ideal for continuous operation in semiconductor manufacturing cleanrooms and plenums, as well as FOUP and EFEM applications. Every analyzer is certified to meet the published specifications.

Performance Specifications	SI3401			
	HCI	HF	NH <sub>3</sub>	H <sub>2</sub> O
Precision	≤75 ppt (10 sec), ≤25 ppt (100 sec)	≤40 ppt (10 sec), ≤13 ppt (100 sec)	≤300 ppt (10 sec), ≤100 ppt (100 sec)	20 ppm + (8 x %H <sub>2</sub> O) (10 sec) 10 ppm + (4 x %H <sub>2</sub> O) (100 sec)
Lower Detectable Limit (100 sec., 3 <i>o</i> )	75 ppt	40 ppt	300 ppt	30 ppm
Method Detection Limit (per Semi C10-1109)	250 ppt	500 ppt	500 ppt	40 ppm
Linearity (per IEC 61207)	±1%	±1%	±1%	±1%
Accuracy at span	±5% @ full scale	±5% @ full scale	±5% @ full scale	±5% @ full scale
Accuracy at zero	±50 ppt	±25 ppt	±150 ppt	±40 ppm
Instrument-to-Instrument Consistency	±5% @ full scale ±50 ppt @ zero	±5% @ full scale ±25 ppt @ zero	±5% @ full scale ±150 ppt @ zero	±5% @ full scale ±40 ppm @ zero
Measurement Range	0–2 ppm	0–1 ppm	0–10 ppm	0–40000 ppm
Measurement Interval*	<9 seconds		<5 seconds	<9 seconds
Sample Flow Rate	~2 sim			
Combined Response Times (T90/10 + T10/90) @ 20 ppb	<3 min			<20 sec (10,000 ppm challenge)
Fall Times T90/10 @ 20 ppb	<1 min			<10 sec (10,000 ppm challenge)

\* Measurement interval at span may increase as much as 2x above listed values.

SI3401 System Specifications			
Measurement Technique	Cavity Ring-Down Spectroscopy		
Operating Temperature	15 to 35°C (operating); -10 to 50°C (storage)		
Ambient Humidity	<85% RH non-condensing		
Accessories	Pump (external, included), keyboard (included), mouse (included), LCD monitor (optional)		
Outputs	RS-232, Ethernet, USB		
Sample Inlet Connection	1/4" Stainless Steel Swagelok® Tube Fitting (recommended 1/4" OD PFA Tubing)		
Dimensions	Analyzer: 16.7" w × 8.4" h x 24.8" d (43 × 21.3 × 63 cm)		
Weight	70 lbs. (31.75 kg) including pump		
Power Requirements	100–240 VAC, 47–63 Hz (auto-sensing), <400 W (total): 250 W (analyzer), 150 W (pump) at steady state		